

# Wakes from Surface Effects in Round Beam Pipes

beam impedance and surface impedance

dielectric layer, roughness

parameters

Gaussian beam

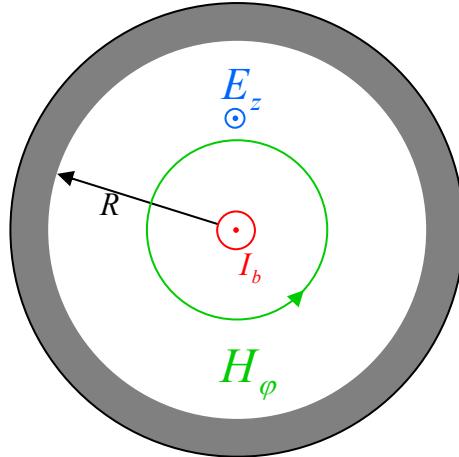
s2e beam



## beam impedance and surface impedance

$$Z'_b = -\frac{E_z}{I_b} \Big|_{r \rightarrow 0}$$

$$Z_s = -\frac{E_z}{H_\varphi} \Big|_{r=R}$$



$$Z'_b(\omega) = \frac{Z_s(\omega)}{2\pi R} \frac{1}{1 + i \frac{\omega}{c} \frac{R}{2} \frac{Z_s(\omega)}{Z_0}}$$

metallic conductor ( $\kappa$ ):  
(plane wave approximation)

$$Z_s^{(\kappa)} \approx \sqrt{\frac{j\omega\mu}{\kappa(\omega)}} \quad \kappa(\omega) \approx \frac{\kappa_0}{1 + i\omega\tau}$$



## surface: dielectric layer

surface impedance of thin dielectric layer ( $\varepsilon_r$ ) on perfect conductor:

$$Z_{s,d}^{(\varepsilon)} \approx j\omega L_d \quad \text{with} \quad L_d = \Delta \cdot \mu \frac{\varepsilon_r - 1}{\varepsilon_r}$$

old assumption:  $\varepsilon_r = 2$

more realistically:  $\varepsilon_r = 10$  (used for the following)

## surface: roughness

$$Z_{s,r}^{(\varepsilon)} \approx j\omega L_r \quad \text{with} \quad L_r \approx \frac{\Delta}{100} \cdot \mu$$

used for the following:  $\Delta \approx 300 \text{ nm}$   
( $\sim 3 \text{ nm}$  dielectric layer)

## multiple surface effects

$$Z_s = Z_s^{(\kappa)} + j\omega(L_d + L_r)$$



# parameters

beam pipe radius **4.4 mm**

## material properties

$$\kappa_{al,0} = 36.6 \cdot 10^6 \frac{1}{\Omega m} \quad \tau_{al} = 0.71 \cdot 10^{-14} s$$

$$\kappa_{cu,0} = 58 \cdot 10^6 \frac{1}{\Omega m} \quad \tau_{cu} = 2.46 \cdot 10^{-14} s$$

$$\epsilon_{r,oxide} = 10$$

$$\Delta_{rough} = 300 \text{ nm}$$

bunch charge 1 nC

peak current 5 kA

I.Zagorodnov, 26.Feb 2007:

T.Wohlenberg WP19 Warm Vacuum Status Report  
XFEL Project Meeting 13.12.2006

<u>Chamber dimensions :</u>	<u>length :</u>	5122mm
	<u>width:</u>	70mm
	<u>height:</u>	9.6mm
	<u>elliptical aperture:</u>	horizontal: 15mm vertical: 8.8mm

### extruded aluminium chamber

Aluminium

$$\sigma = 3.66 \cdot 10^7 [\Omega^{-1} m^{-1}]$$

$$\tau = 7.1 \cdot 10^{-15} [\text{sec}]$$

$$\Delta_{rough} = 600 [\text{nm}]$$

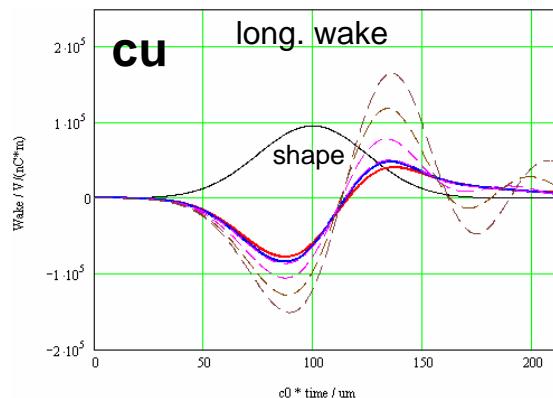
$$\Delta_{oxid} = 5 [\text{nm}]$$

$$\epsilon_{r,oxide} = 2$$

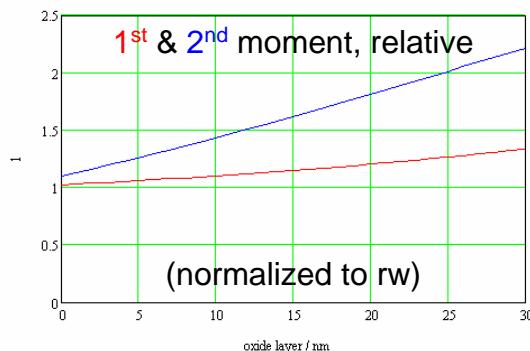
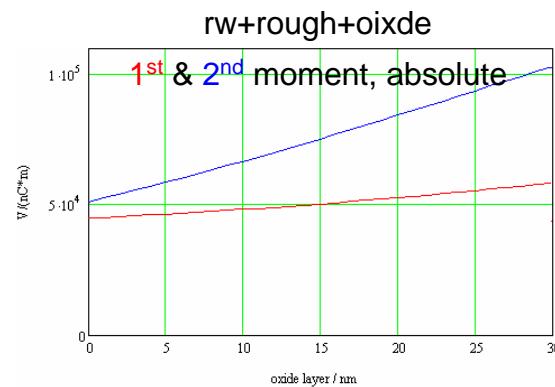
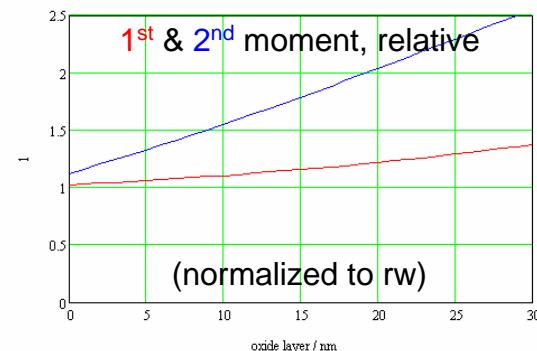
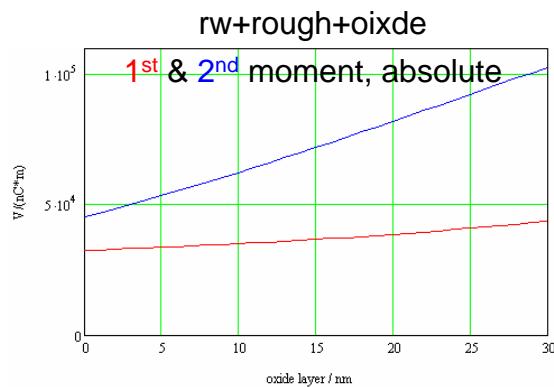
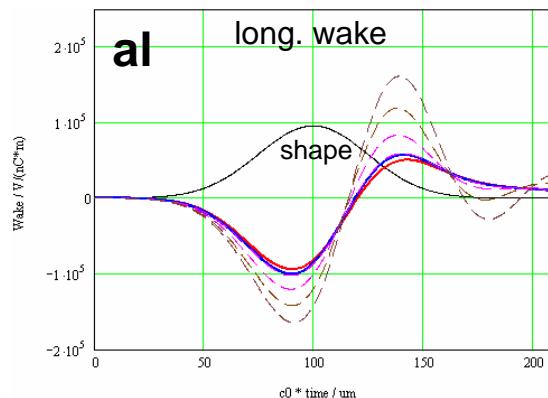
Elliptical chamber length = 5122 mm



# Gaussian beam

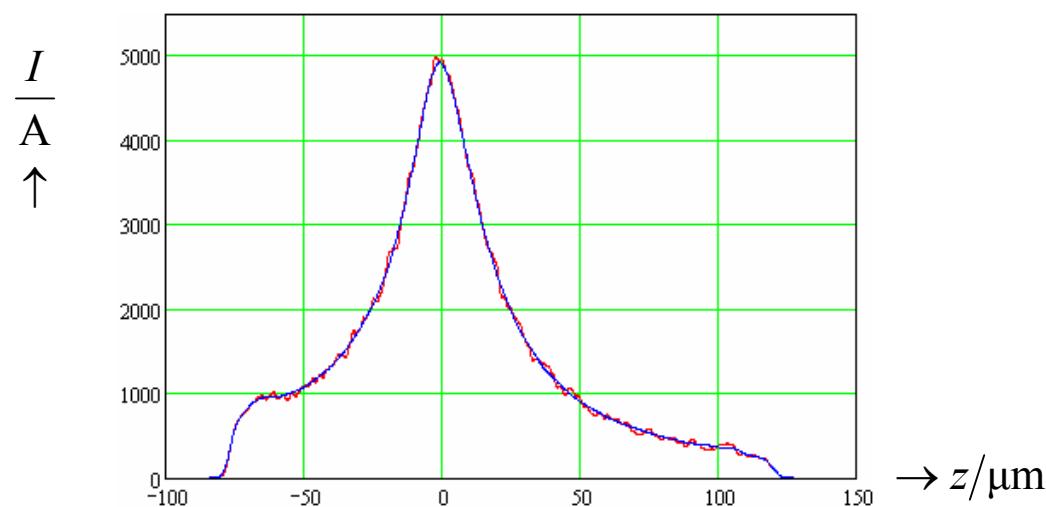
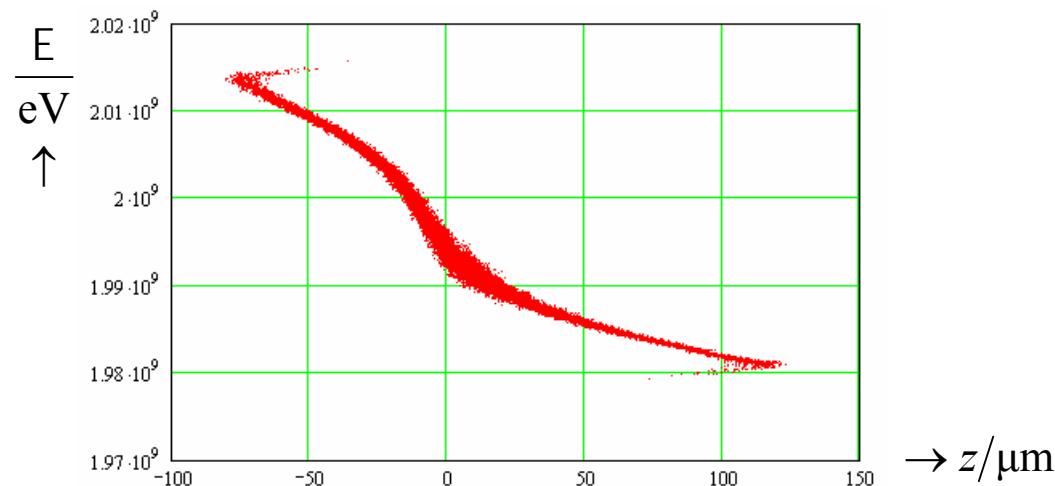


rw+rough+30nm ox  
 rw+rough+20nm ox  
 rw+rough+10nm ox  
 rw+rough+ 1nm ox  
 rw+rough (300nm)  
**rw**

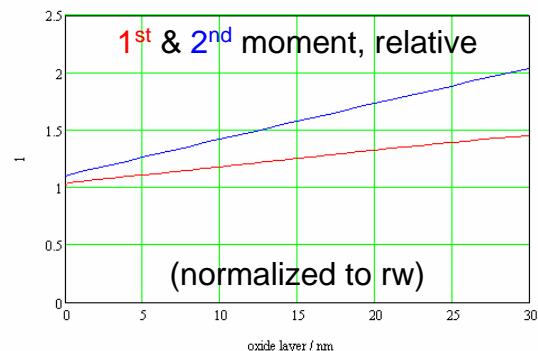
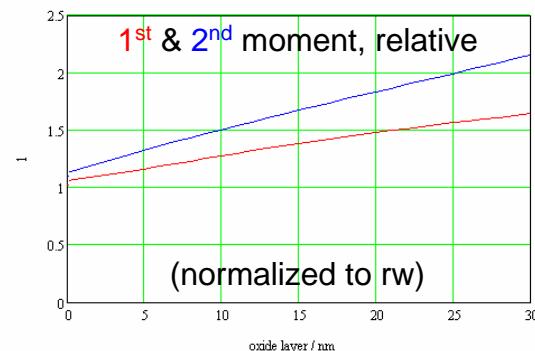
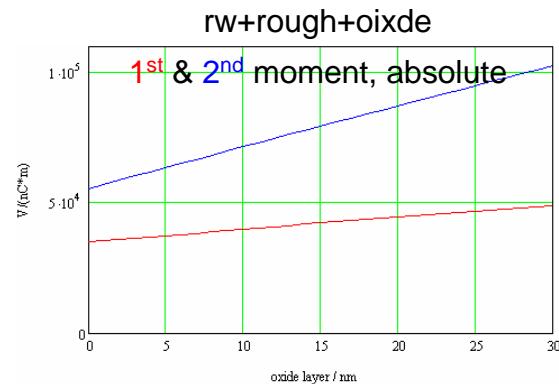
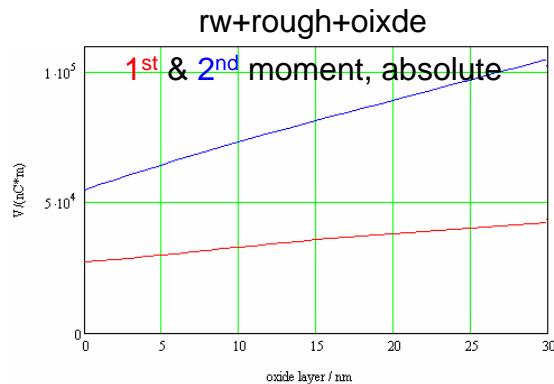
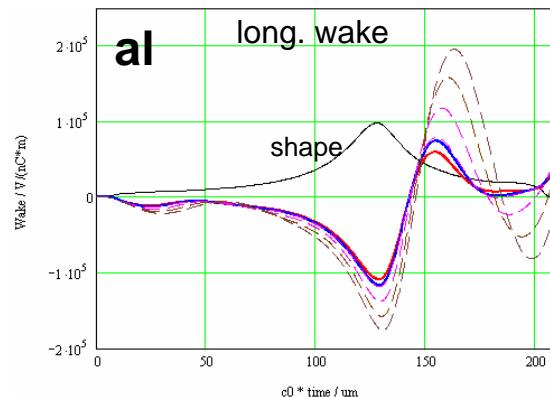
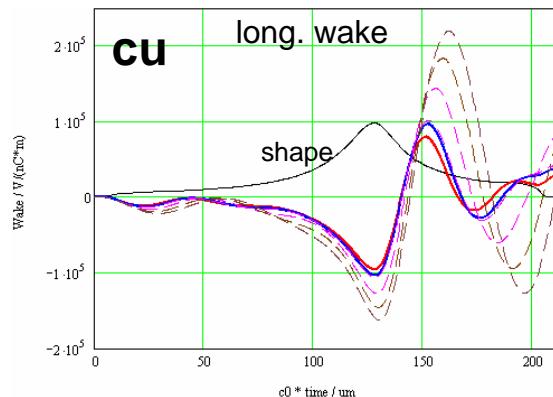


## s2e beam

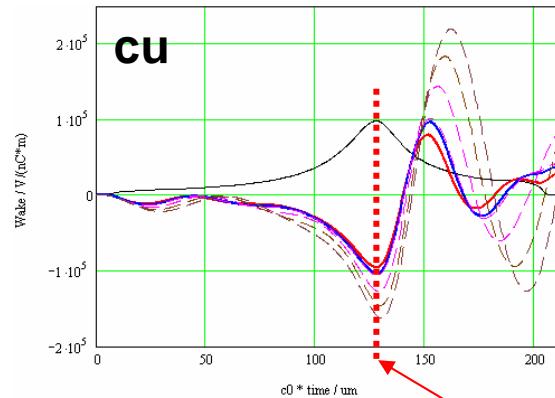
bunch shape from the “official” start to end simulation (December 2005)



# s2e beam

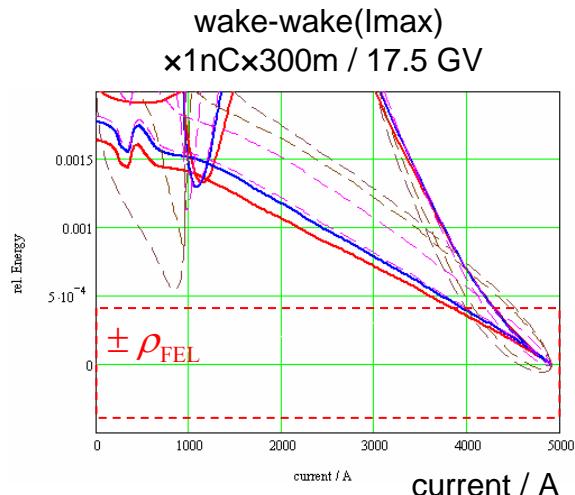
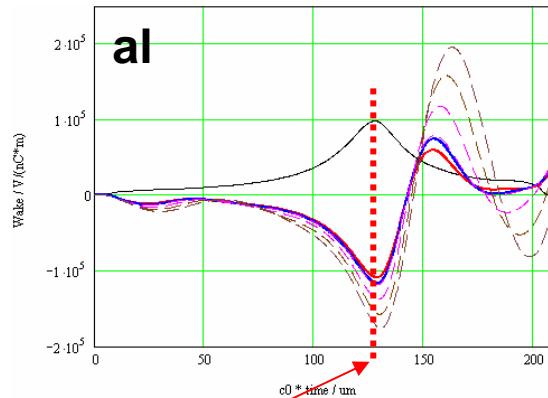


# s2e beam – dE vs. current

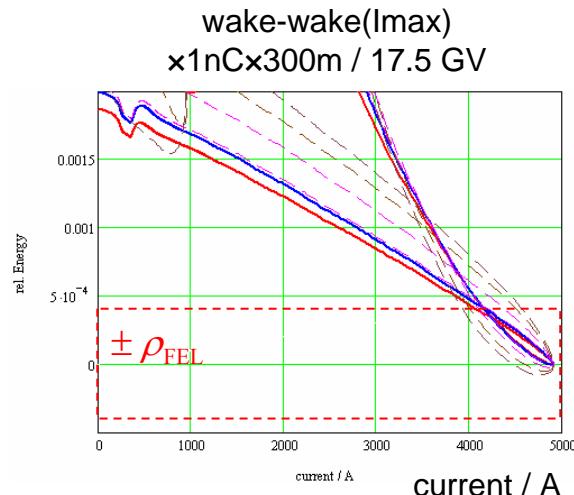


$\text{rw+rough+30nm ox}$   
 $\text{rw+rough+20nm ox}$   
 $\text{rw+rough+10nm ox}$   
 $\text{rw+rough+ 1nm ox}$   
 $\text{rw+rough (300nm)}$   
**rw**

energy loss (in undulator) compensated by tapering for this working point !



$\sigma_{\text{FEL}} \approx 4 \times 10^{-4}$   
(FEL parameter)



→ surface effects might increase FEL bandwidth significantly

